

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No.09/810,387
Filing Date March 15, 2001
Confirmation No. 8779
Inventor..... Craig M. Carpenter
AssigneeMicron Technology, Inc.
Group Art Unit 1792
Examiner Rudy Zervigon
Attorney's Docket No. MI22-1559
Title:.....Chemical Vapor Deposition Apparatuses and Deposition Methods

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

References - - See attached Form PTO/SB/08A-B

In compliance with 37 C.F.R. §§ 1.56, 1.97 and 1.98, your attention is directed to the United States patents and other references listed on the attached Form PTO/SB/08. Copies of the cited art are included with the exception of U.S. patents and published U.S. applications (1273 Off. Gaz. Pat. Off. 55, 05 August 2003). No admission is made regarding whether all the submitted references are prior art.

This Information Disclosure Statement is being filed before the mailing of a first office action after the filing of a request for continued examination. Therefore, no fee is believed to be required. However, in the event that a fee is required for filing this Information Disclosure Statement, please charge the fee, any underpayment or credit any overpayment specified under 37 C.F.R. § 1.17(p) to Deposit Account No. 23-0925.

Citation of these references is respectfully requested.

Respectfully submitted,

Dated: 14 October 2008

/James E. Lake/
By: _____
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